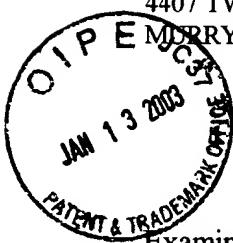


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner: Moore, Karla A.

Docket: SACHER II-Div

Applicant(s): Dr. Joachim Sacher et al.

Serial No.: 09/902,882

In Response To
Paper No: 7

Filing Date: 12/July/01

Art Unit: 1763

Title: COATING PROCESS AND APPARATUS

RECEIVED
JAN 17 2003
TC 1700

Hon. Commissioner of Patents and Trademarks
Washington, DC 20231

January 9, 2003

RECEIVED
JAN 16 2003
TECHNOLOGY CENTER 1700

SIR:

Enclosed herewith is a petition for an extension of time by one month for responding to the official action dated 09/30/02, so that the new due date is 01/30/03.

Also enclosed herewith is a certified copy of German application 198 12 562.3 in support of the claim for priority.

In response to the Official Action dated 09/30/02, please amend the present application as follows:

C1
14. An apparatus for coating at least one of the front and rear facets of semiconductor laser diodes (lasers) with an anti-reflection layer of minimal rest reflectivity, said apparatus including means for monitoring, in-situ, at least one of laser parameters of each laser, including laser light

Sub

C1 out

emitted from at least one of the front and rear facets of each laser, the electric voltage at a p-n junction of the laser, the quantum efficiency of the laser light emitted from at least one of the front and rear facet of the laser, and the threshold current of the laser, said apparatus comprising a receiver for containing lasers to be coated, a coating source disposed in said receiver, a support structure for supporting said lasers to be coated such that said lasers are supported with their facets all at essentially the same distance from said coating source, and for each laser a shutter supported in said receiver so as to be movable selectively in front of lasers to protect them from further coating.

C2

17. An apparatus according to claim 14, wherein said lasers are arranged linearly along lines disposed at opposite sides equidistantly from a center line.

Sub

18. An apparatus according to claim 14, wherein a control unit is provided which monitors the laser parameter of said lasers disposed in said receiver for the coating thickness of their facets while each laser is electrically operated.

REMARKS

Concerning the Examiner's rejection of claim 17, the above amendment should overcome the examiners rejection under 35 USC 112, first paragraph.

Reconsideration is respectfully requested.

The Examiner has rejected claims 14 – 16 and 18 – 20 under 35 USC 103(a) as being obvious from US 6 037 006 in view of US 5 221 636.

It is pointed out however that US 6 037 006 discloses an apparatus for the surface-coating of facets of diode laser bars. The apparatus comprises a vacuum chamber 160, an electron beam source 168 for vaporizing coating material, and a rotation structure 164, which supports a plurality of fixtures 20 for holding diode laser bars 90. Web slats 50-1 to 50-n are